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APPLICANT'S ART CITATION (Use several sheets if necessary)		Application 10/045,973		OFGS File No. P/2292-52			
		Applicant Kyoung-Ri PARK et al					
		Filing Date January 10, 2002		Group Art Unit 1751			
U.S. PATENT DOCUMENTS							
Examiner Initial	Document Number	Date MM-YYYY	Name	Class	Sub- class	Filing Date If Appropriate	
	US-						
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FOREIGN PATENT DOCUMENTS							
	Document Number	Date MM-YYYY	Country	Class	Sub- class	Translation	
						Yes	No
<i>KW</i>	55-078406	06-1980	Japan				X
<i>ICW</i>	06-251863	09-1994	Japan				X
<i>KW</i>	61-032376	02-1986	Japan				X
<i>KW</i>	62-138701 62-004750	06-1988	Japan				X
<i>KW</i>	63-138701	01-1987	Japan				X
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
<i>KW</i>		Untranslated Japanese Office Action issued against corresponding Japanese application no. 2002-136543 dated February 6, 2004					
<i>ICW</i>		English translation of Abstract for Japanese Laid-open application no. 55-078406					
<i>KW</i>		English translation of Abstract for Japanese Laid-open application no. 06-251863					
<i>ICW</i>		English translation of Abstract for Japanese Laid-open application no. 61-032376					
<i>KW</i>		English translation of Abstract for Japanese Laid-open application no. 63-138701					
<i>KW</i>		English translation of Abstract for Japanese Laid-open application no. 62-004750					
Examiner <i>YAL</i>		Date Considered <i>May 14, 2009</i>					
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.							